

FORM PTO-1449

LIST OF PATENTS AND PUBLICATIONS FOR
APPLICANT'S INFORMATION DISCLOSURE
STATEMENT

(Use several sheets if necessary)

ATTY. DOCKET NO.

10007140

APPLICATION NO.

CONFIRMATION NO.

APPLICANT

Heon Lee

FILING DATE

01/30/02

GROUP

REFERENCE DESIGNATION

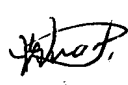
U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
	2A					
	2B					
	2C					
	2D					
	2E					
	2F					
	2G					
	2H					
	2I					
	2J					
	2K					

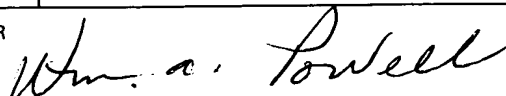
FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	TRANSLATION	
							YES	NO
	2L							
	2M							
	2N							
	2O							
	2P							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

	2Q	Roller nanoimprint lithography Hua Tan, Andrew Gilbertson, & Stephen Y Chou @1998 american Vacuum Society J Vac Sci Technol. B 16(6), Nov/Dec 1998, pg 3926
	2R	Large area high density quantized magnetic disks fabricated using nanoimprint lithography Wei Wu, Bo Cui, Xiao-yun Sun, Wei Zhang, Lei Zhuang, Linshu Kong and Stephen Y Chou @1998 american Vacuum Society J Vac Sci Technol. B 16(6), Nov/Dec 1998, pg 3825
	2S	Multilayer resist methods for nanoimprint lithography on nonflat surfaces Ziaoyun Sun, Lei Zhuang, Wei Zhang, and Stephen Y Chou @1998 american Vacuum Society J Vac Sci Technol. B 16(6), Nov/Dec 1998, pg 3922

EXAMINER



DATE CONSIDERED

08/22/03

PATENT APPLICATION

Sheet 3 of 3

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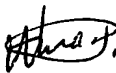
U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
	3A					
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	3C					
	3D					
	3E					
	3F					
	3G					
	3H					
	3I					
	3J					
	3K					

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		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	TRANSLATION	
							YES	NO
	3L							
	3M							
	3N							
	3O							
	3P							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

	3Q	Pillars in Perfect Order By Steven Schultz Princeton Weekly Bulletin, November 22, 1999, vol. 89, No. 20
	3R	Esprit Project 28785 - Nanotect Development of Nanoimprinting technique suitable for large area mass production of nm-scale patterns Dr Lars Montelius, Lund University Dept of physics Professorsgatan
	3S	

EXAMINER



DATE CONSIDERED

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FILING DATE

01/31/02

GROUP

10/06/2952
01/31/02
Jc979 U.S. PTO

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
<i>Handwritten</i>	1A	5772905	06/30/98	Chou	I	I
	1B	5875071	02/23/99	Erpelding, et al.	I	I
	1C	6117344	09/12/00	Cox, et al.	I	I
	1D	6069380	05/30/00	Chou, et al.	I	I
<i>Handwritten</i>	1E	6309580	10/30/01	Chou	I	I
	1F					
	1G					
	1H					
	1I					
	1J					
	1K					

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	TRANSLATION	
							YES	NO
	1L							
	1M							
	1N							
	1O							
	1P							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

<i>Handwritten</i>	1Q	Researchers Seek Workable Techniques for Nanoelectronics By Chappell Brown, EE Times Jan 17, 2001 url: http://www.eetimes.com/story/oeg20010117S0071
	1R	Big Push on A Nano Scale By Chappell Brown, EE Times, Issue 1150, Monday January 22, 2001
<i>Handwritten</i>	1S	A Self-Aligned Offset Polysilicon Thin-film Transistor Using Photoresist Reflow Jung-In Han and Chul-Hi Han IEEE Electron Device Letters, Vol. 20, NO. 9, September 1999

EXAMINER

Handwritten: Wm. a. Powell

DATE CONSIDERED

Handwritten: 08/22/03